



AF / IPFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: § Attorney Docket No. 24061.49
Chih-Wei Hsu § (2003-0125)

Serial No.: 10/791,930 § Customer No. 42717

Filed: March 3, 2004 § Group Art Unit: 2125

For: SYSTEM AND METHOD FOR § Examiner: Kosowski, Alexander J.
PROCESS CONTAMINATION §
PREVENTION FOR SEMICONDUCTOR §
MANUFACTURING §

RESPONSE

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed September 19, 2005, please reconsider the application in light of the following amendments and remarks:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 8 of this paper.